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a probe with a high aspect ratio is used as said probe and said probe measures topographic features with a high aspect ratio formed on a semiconductor substrate.

A3

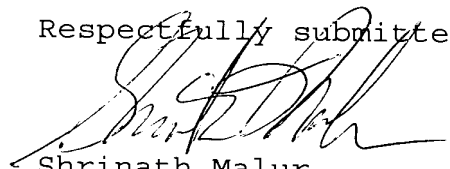
24. (Amended) A scanning probe microscope as set forth in claim 19 [or 21], wherein said movement mechanism is a sample stage for carrying said sample and making said sample move in the scan direction in millimeter units of length.

REMARKS

Claims 7, 13 and 24 have been amended to remove multiple dependencies.

Examination is respectfully requested.

Respectfully submitted,

  
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